The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a pattern of a light emitting layer comprising the organic electroluminescence material over a substrate,

wherein the evaporation cell comprises a tip formed into an orifice.

2. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a pattern of a light emitting layer comprising the organic electroluminescence material over a substrate by opening and closing the shutter,

wherein the evaporation cell comprises a tip formed into an orifice.

3. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device,

wherein the evaporation cell comprises a tip formed into an orifice.

4. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device by opening and closing the shutter,

wherein the evaporation cell comprises a tip formed into an orifice.

5. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein more than one evaporation cell is provided.

6. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein more than one evaporation cell is provided.

7. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein more than one evaporation cell is provided.

8. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein more than one evaporation cell is provided.

9. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

10. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

11. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

12. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

13. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the organic electroluminescence material is a small molecule material.

14. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the organic electroluminescence material is a small molecule material.

15. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the organic electroluminescence material is a small molecule material.

16. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the organic electroluminescence material is a small molecule material.

17. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure.

18. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure.

19. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure.

20. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the organic electroluminescence material is heated in an inert gas atmosphere at an atmospheric pressure.

21. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light emitting device; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a tip formed into an orifice.

22. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device by opening and closing the shutter; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a tip formed into an orifice.

23. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the evaporation cell is moved.

24. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the evaporation cell is moved.

25. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

26. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

27. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

28. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

29. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

30. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

31. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein a diameter of the orifice is several tens to several hundreds μm.

32. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein a diameter of the orifice is several tens to several hundreds μm.

33. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein a diameter of the orifice is several tens to several hundreds μm.

34. (Previously Presented) The method of manufacturing a light-emitting device according to claim 1 wherein said pattern is directly deposited from said evaporation cell.

35. (Previously Presented) The method of manufacturing a light-emitting device according to claim 2 wherein said pattern is directly deposited from said evaporation cell.

36. (Previously Presented) The method of manufacturing a light-emitting device according to claim 1 wherein said pattern is formed over said substrate without the use of a mask.

37. (Previously Presented) The method of manufacturing a light-emitting device according to claim 2 wherein said pattern is formed over said substrate without the use of a mask.

38. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic electroluminescence material, said evaporation cell comprising a tip formed into an orifice adapted to directly deposit a pattern of a ~~light-emitting~~ light emitting layer comprising the organic electroluminescence material over a substrate; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form the pattern of [[a]] the light emitting layer comprising the organic electroluminescence material over the substrate.

39. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the evaporation cell is moved.

40. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

41. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein a diameter of the orifice is several tens to several hundreds μm.

42. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the substrate is moved in X-Y directions.

43. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the substrate is moved in X-Y directions.

44. (Currently Amended) A method of manufacturing a light-emitting device according to claim 1, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

45. (Currently Amended) A method of manufacturing a light-emitting device according to claim 2, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

46. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

47. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

48. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

49. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein a pattern of the light emitting layer has a width of about 50 to 200μm.

50. (Currently Amended) A method of manufacturing a light-emitting device according to claim 38, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

51. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

preparing an evaporation cell filled with an organic material,

evaporating the organic material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell;

forming a pattern comprising the organic material over a substrate; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a tip formed into an orifice.

52. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein more than one evaporation cell is provided.

53. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

54. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

55. (Currently Amended) A method of manufacturing a light-emitting device according to claim 51, wherein the pattern of the light emitting layer has a width of about 50 to 200μm.

56. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein a diameter of the orifice is several tens to several hundreds μm.

57. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein a diameter of the orifice is several tens to several hundreds μm.

58. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein a diameter of the orifice is several tens to several hundreds μm.

59. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein a diameter of the orifice is several tens to several hundreds μm.

60. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the organic electroluminescence material is ejected through the orifice.

61. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the organic electroluminescence material is ejected through the orifice.

62. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein the organic electroluminescence material is ejected through the orifice.

63. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein the organic electroluminescence material is ejected through the orifice.

64. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the organic electroluminescence material is ejected through the orifice.

65. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the organic electroluminescence material is ejected through the orifice.

66. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the organic electroluminescence material is ejected through the orifice.

67. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein the organic electroluminescence material is ejected through the orifice.